

EV317135795

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No. 10/039,456
Priority Filing Date December 31, 2001
Inventor Ying Huang et al.
Assignee Micron Technology, Inc.
Priority Group Art Unit 2829
Priority Examiner S.B. Geyer
Attorney's Docket No. MI22-2347
TITLE: An Improved Method, Structure and Process Flow to Reduce Line-Line
Capacitance with Low-K Material

Commissioner for Patents
Alexandria, VA 22313-1450

Attention: Official Draftsman

SUBSTITUTE DRAWING REQUEST

Please enter the enclosed substitute drawings in the above-referenced application
in place of drawings originally filed. The content of the drawings are identical to those now
on file in this application.

Acknowledgment of receipt of the formal drawings and their acceptance into the file
is requested.

Respectfully submitted,

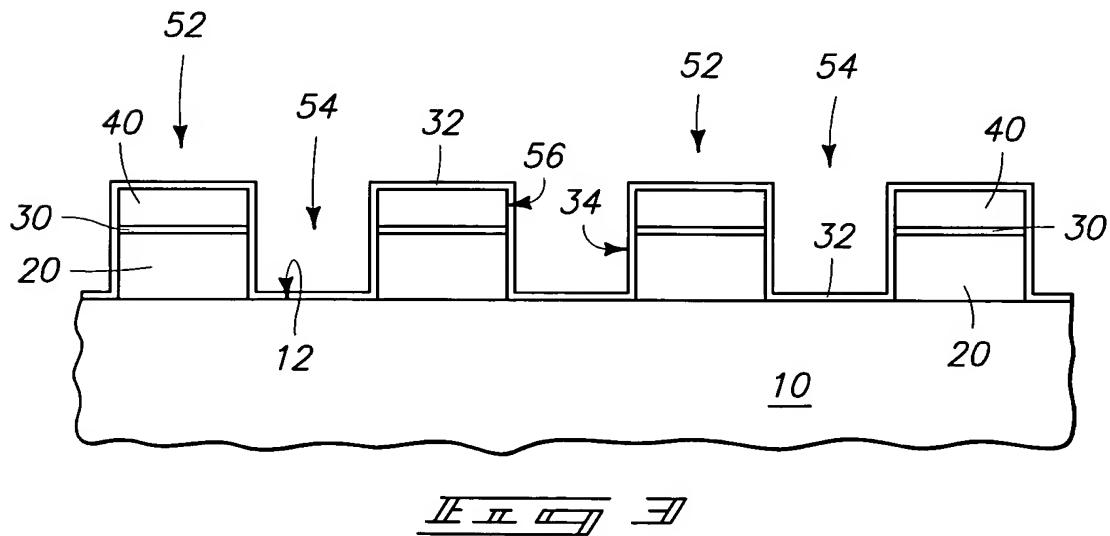
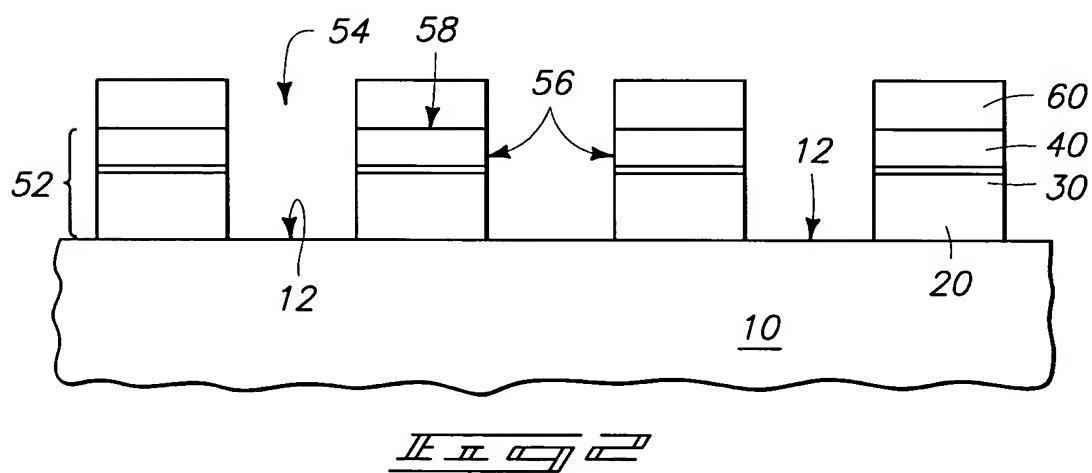
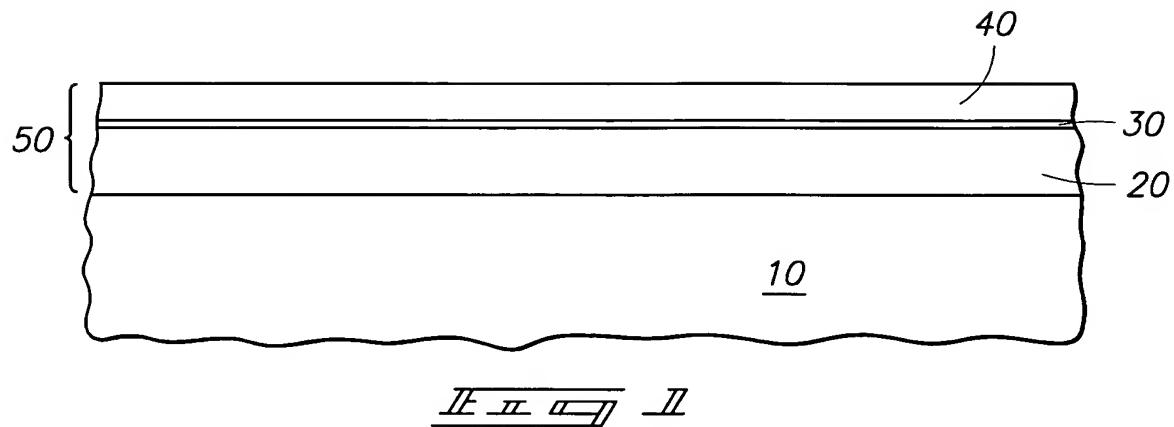
Date: 7-23-03

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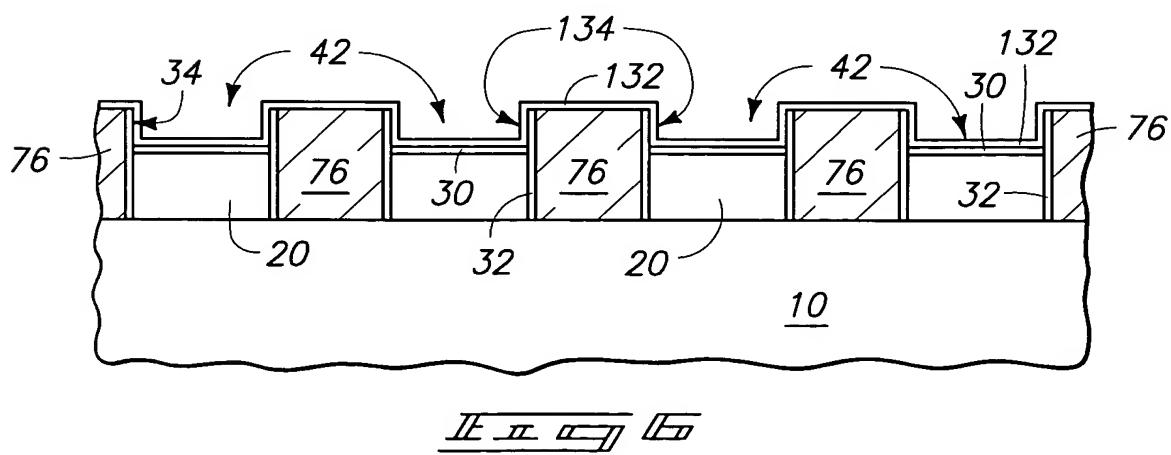
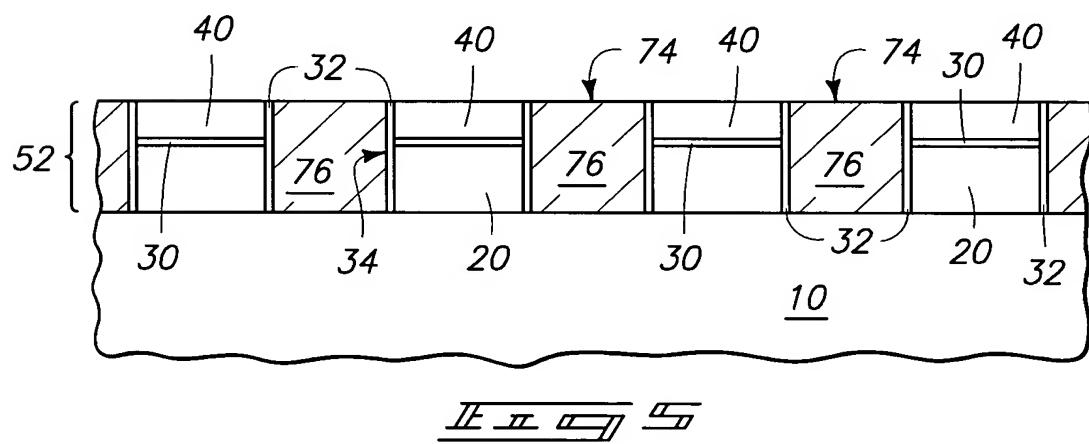
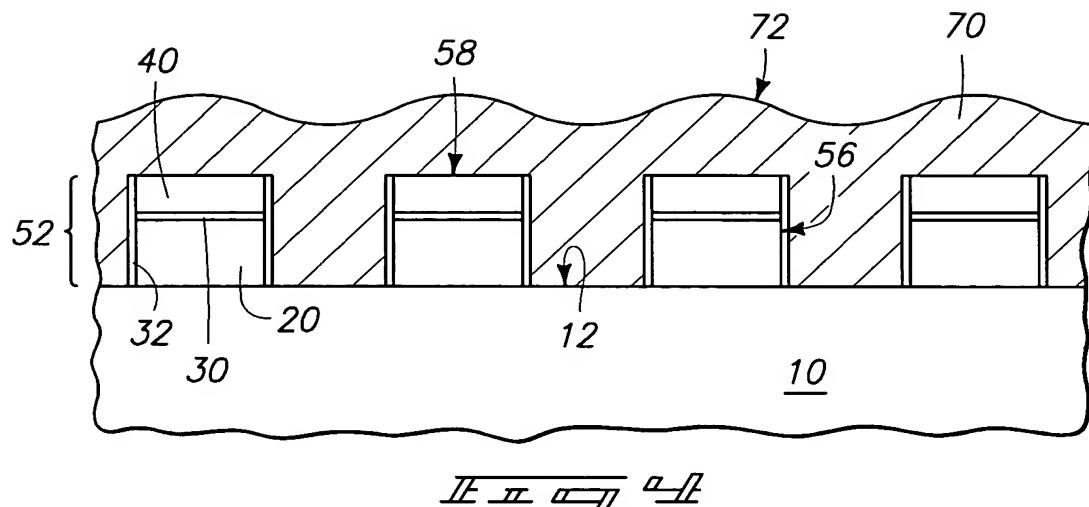

D. Brent Kenady
Reg. No.: 40,045
WELLS ST. JOHN P.S.
601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828
(509) 624-4276

Enclosures: 5 Sheets of Formal Drawings, Figs. 1-14.

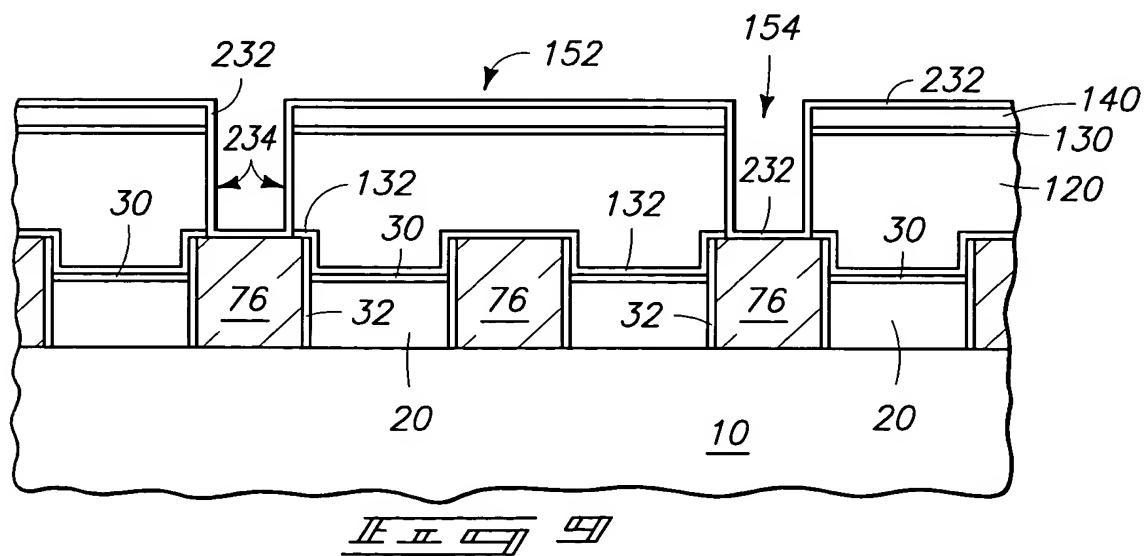
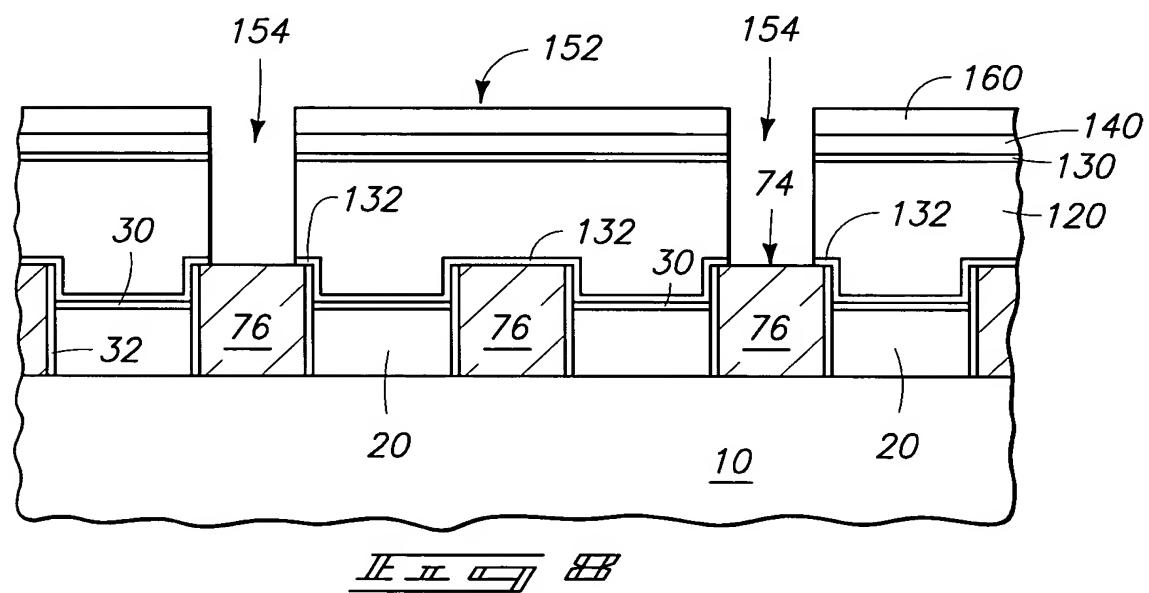
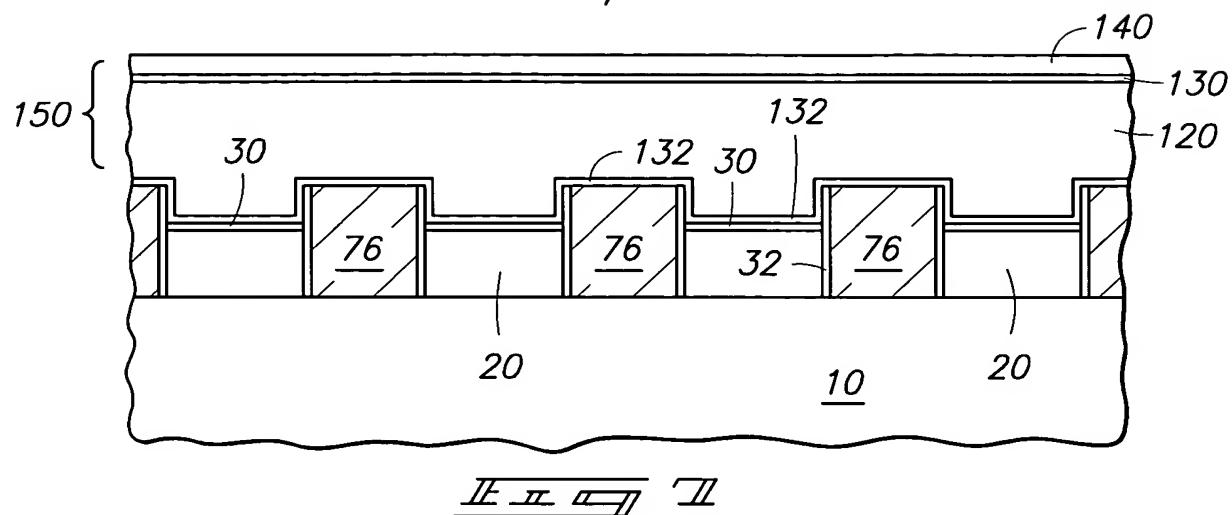
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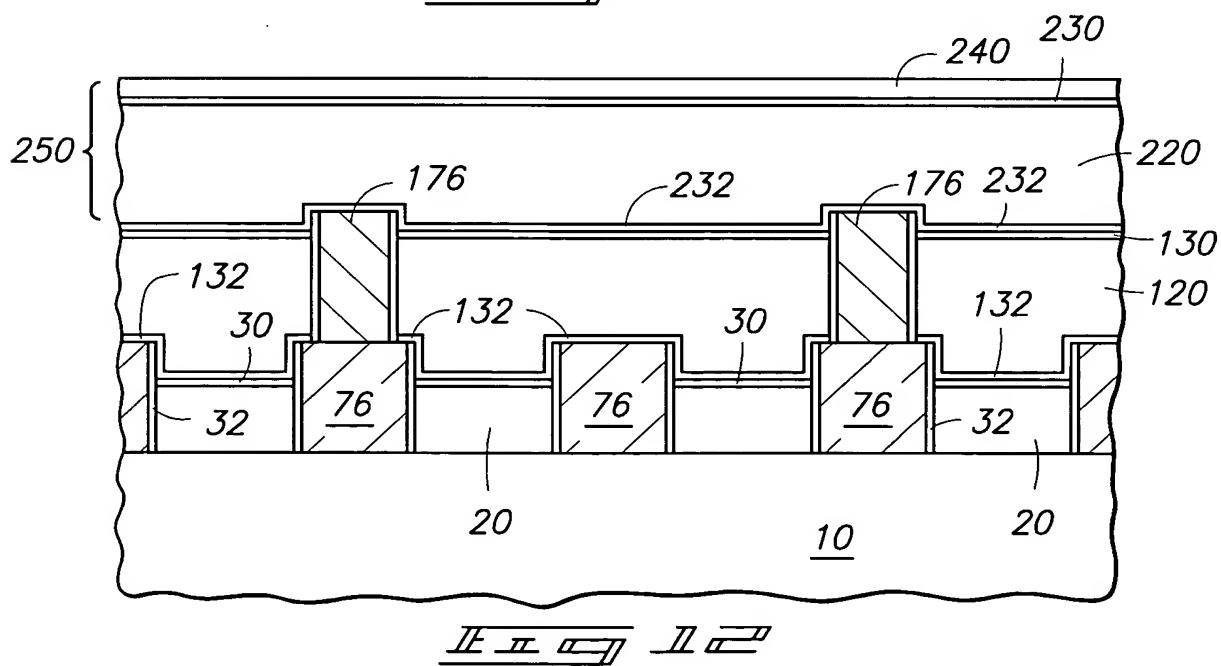
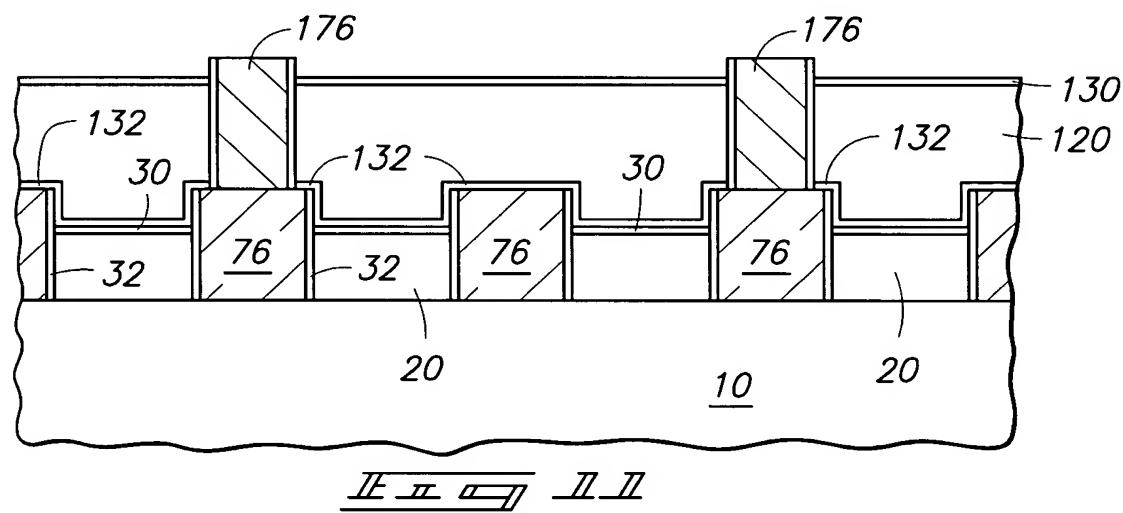
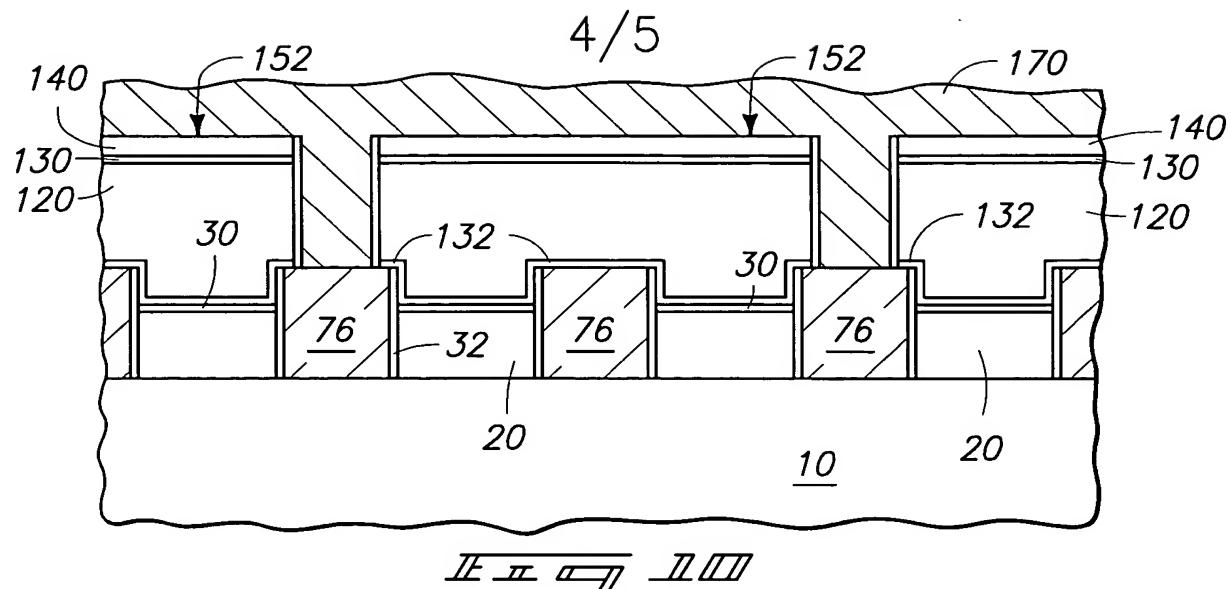


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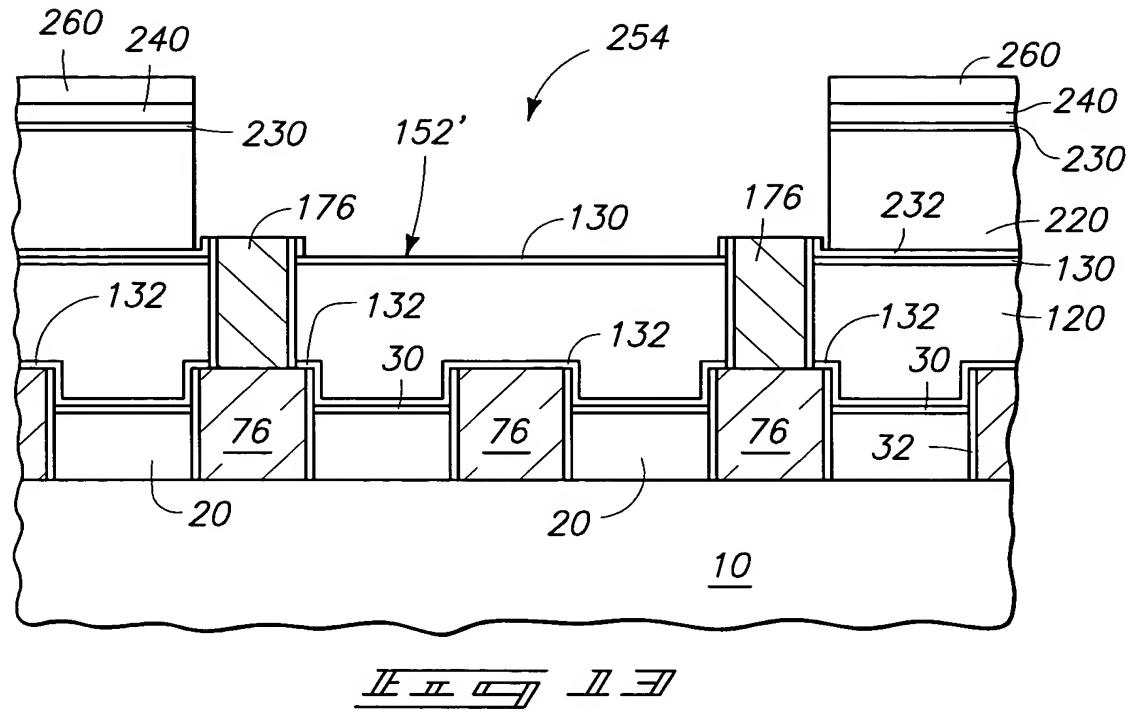
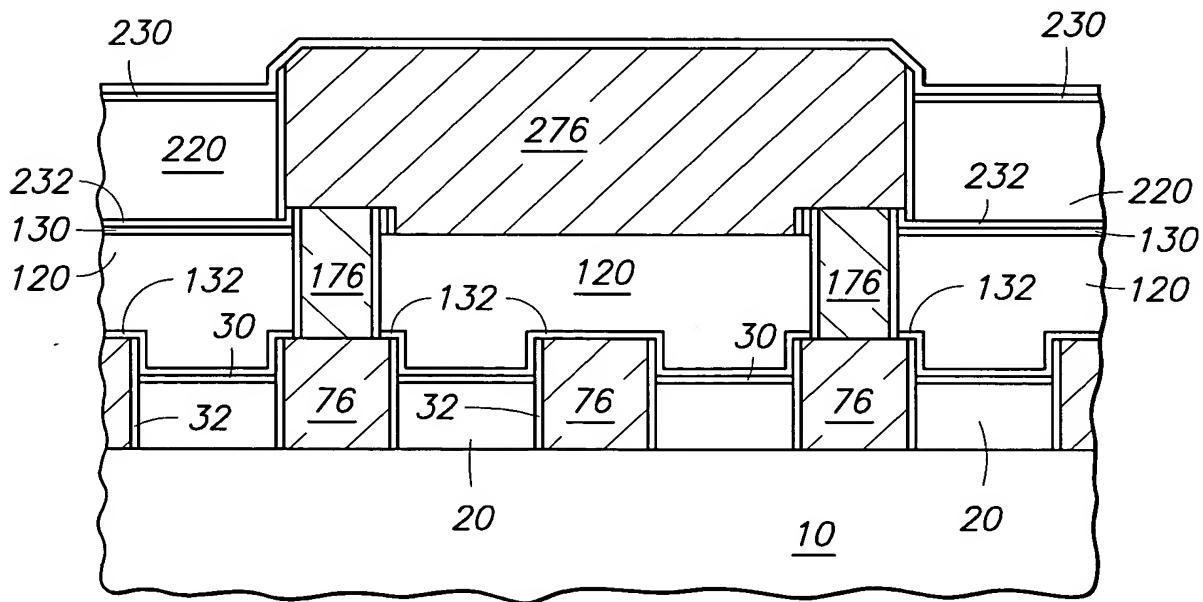


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